L Number	Hits	Search Text	DB	Time stamp
_	8	118/719.ccls. and (chamber with pressure	USPAT;	2003/04/06 16:1
		with higher with prevent)	US-PGPUB	
_	1	("20010040145").PN.	USPAT;	2003/02/26 10:1
			US-PGPUB	
_	3	(("5709785") or ("6251191") or	USPAT;	2003/04/04 16:5
	,	("4576830")).PN.	US-PGPUB	
	1	("6358377").PN.	USPAT;	2003/04/04 17:0
_		(03303//).EN.	US-PGPUB	2003/04/04 1/.0
		5050000 WDDV		2003/04/04 17:0
-	0	6358377.URPN.	USPAT	
-	1	("6228439").PN.	USPAT;	2003/04/04 17:0
			US-PGPUB	
- .	1	6228439.URPN.	USPAT	2003/04/04 17:0
_	1	6228439.URPN.	USPAT	2003/04/04 17:0
_	329	118/719.ccls. and (conveyor track rail)	USPAT;	2003/04/04 17:0
	l	_	US-PGPUB	
_	38	118/719.ccls. and (conveyor track rail)	USPAT;	2003/04/04 17:0
		and cluster	US-PGPUB	
_	۹ ا	6235634.URPN.	USPAT	2003/04/04 17:1
_	124	414/\$.ccls. and (conveyor track rail) and	USPAT;	2003/04/04 17:2
_	124		US-PGPUB	2003,01,01 2:12
		cluster and (rotat\$3) 414/\$.ccls. and (conveyor track rail) and	USPAT;	2003/04/04 18:3
-	53	414/9.CCIS. and (Conveyor track rail) and		2003/04/04 10:3
		cluster and (rotat\$3) and (substrate water	US-PGPUB	
		semiconductor)		0000/01/01 1= =
<u></u>	72	4643629.URPN.	USPAT	2003/04/04 17:5
	72	4643629.URPN.	USPAT	2003/04/04 17:5
_	28	4674621.URPN.	USPAT	2003/04/04 18:0
_	481	414/\$.ccls. and ((conveyor track rail)	USPAT;	2003/04/04 18:3
		same (turntable))	US-PGPUB	
_	12	414/\$.ccls. and ((conveyor track rail)	USPAT;	2003/04/04 18:5
	1-2	same (turntable with rotat\$3) same	US-PGPUB	
		(substrate wafer semiconductor))	00 10100	
	(27		USPAT;	2003/04/06 14:5
_	677	(414/749.1-749.6).CCLS.		2003/04/00 14.3
•			US-PGPUB	0002/04/06 15:0
_	55	(414/749.4).CCLS.	USPAT;	2003/04/06 15:0
		·	US-PGPUB	
_	279	(414/936).CCLS.	USPAT;	2003/04/06 15:5
	1		US-PGPUB	•
_	72	4643629.URPN.	USPAT	2003/04/06 15:1
-	3548126	414/939.ccls. no ((414/936).CCLS.)	USPAT;	2003/04/06 15:5
			US-PGPUB	
_	485	414/939.ccls.	USPAT;	2003/04/06 15:5
	,,,,,,,	111, 303.0013.	US-PGPUB	
	426	414/939.ccls. not ((414/936).CCLS.)	USPAT;	2003/04/06 15:5
_	420	414/939.0013. NOC ((414/930/.0015.)	US-PGPUB	2003,01,00 10.0
	406	414 (020 1 + (/414 (026) OCEG)		2003/04/06 15:5
-	426	414/939.ccls. not ((414/936).CCLS.)	USPAT;	2003/04/00 13:5
	_		US-PGPUB	0000 /04 /05 15 0
-	69	l '	USPAT	2003/04/06 16:0
-	414		USPAT;	2003/04/06 17:4
		substrate) with vertical\$3)	US-PGPUB	
-	28	4717461.URPN.	USPAT	2003/04/06 16:2
-	62	4500407.URPN.	USPAT	2003/04/06 20:2
-	1	("5888303").PN.	USPAT;	2003/04/06 17:4
	1		US-PGPUB	
_	2	118/719.ccls. and (rotat\$3 with axis with	USPAT;	2003/04/06 17:5
		vertical\$3 with (transfer\$3 transport\$3)	US-PGPUB	
		with chamber)	35 15105	
	1		USPAT;	2003/04/06 17:5
_	91	l · · ·	1	2003/04/06 1/:3
		(transfer\$3 transport\$3) with chamber)	US-PGPUB	0000 /04 /05 15 5
-	802	118/730.ccls.	USPAT;	2003/04/06 17:5
			US-PGPUB	
-	55	156/345.55.ccls.	USPAT;	2003/04/06 18:0
			US-PGPUB	
_	125	156/345.55.ccls. 156/345.54.ccls.	USPAT;	2003/04/06 18:0
			US-PGPUB	
	1.	414/\$.ccls. and (conveyor track rail) and	USPAT;	2003/04/06 18:0
_	155			
-	155		1	
_		cluster	US-PGPUB	2003/04/06 19:0
-	155 43232	cluster 118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.	US-PGPUB USPAT;	2003/04/06 19:0
-		cluster 118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls. and ((vertical\$3 with (substrate wafer	US-PGPUB	2003/04/06 19:0
-		cluster 118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.	US-PGPUB USPAT;	2003/04/06 19:0

_	(118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.) and ((vertical\$3 with (substrate wafer semiconductor) with (transfer\$3	USPAT; US-PGPUB	2003/04/06 19:10
	transport\$3)) same cluster) 5738767.URPN.	USPAT	2003/04/06 19:12

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